



FLAG-ERA JTC 2019 Project

2D-Material Heterostructure NEMS Sensors (2D-NEMS)

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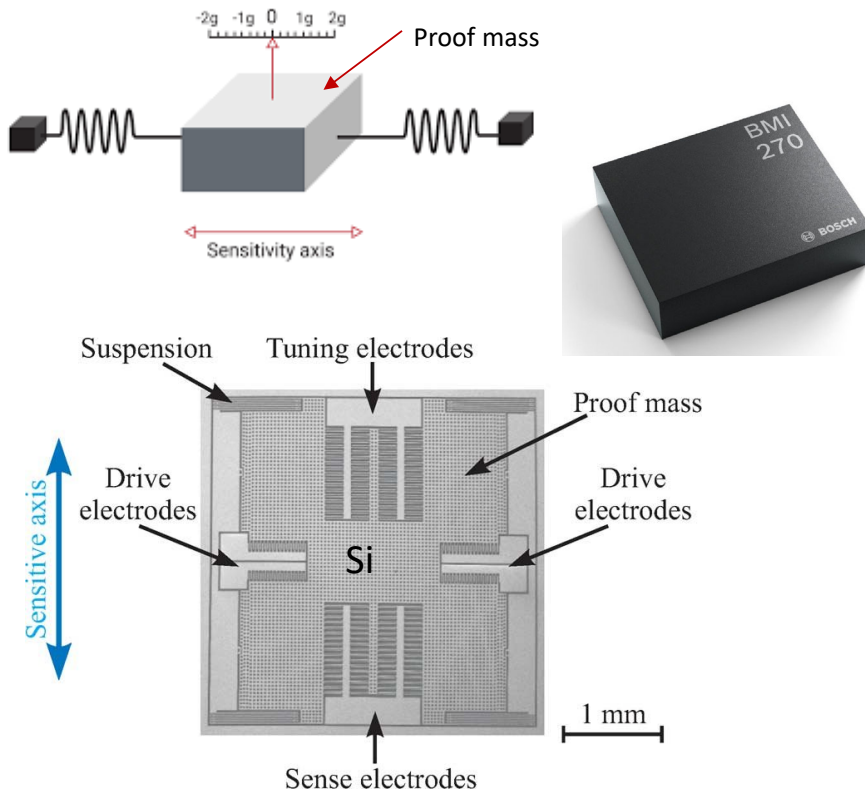
RWTH Aachen University, Germany

Graphenea, Spain



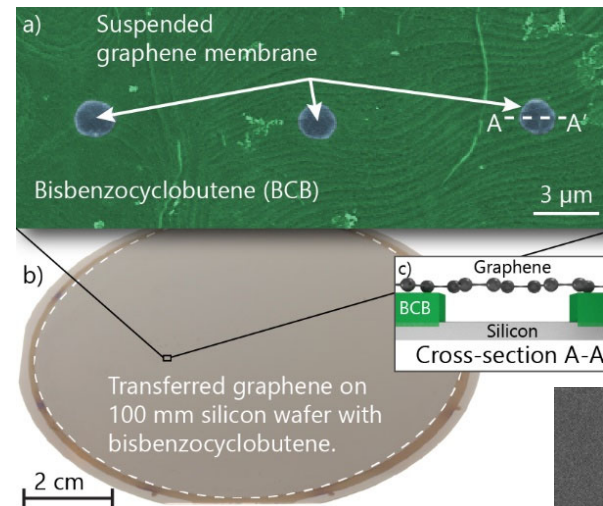
Motivation behind 2D-NEMS

Conventional MEMS sensor



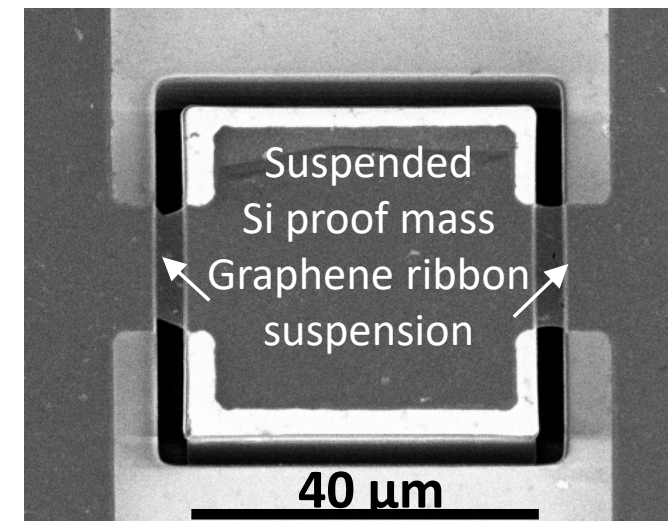
Further miniaturization is hampered by limitations of current Si-based materials.

2D material approach



2D material heterostructures can increase sensitivity and thus enable smaller and cheaper sensors.

Top view



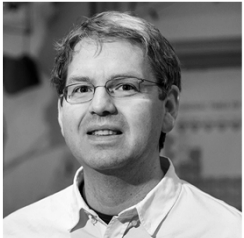


Objectives of 2D-NEMS

1. Realization and electromechanical characterization of suspended 2D material heterostructures with attached proof masses.
2. Exploration and evaluation of scalable integration technologies for realizing suspended 2D material heterostructures.
3. Realization of NEMS sensor concepts based on suspended 2D material heterostructures and their performance characterization.



2D-NEMS consortium



Kristinn Gylfason



Frank Niklaus



Max Lemme



Christoph Stampfer



Amaia Zurutuza

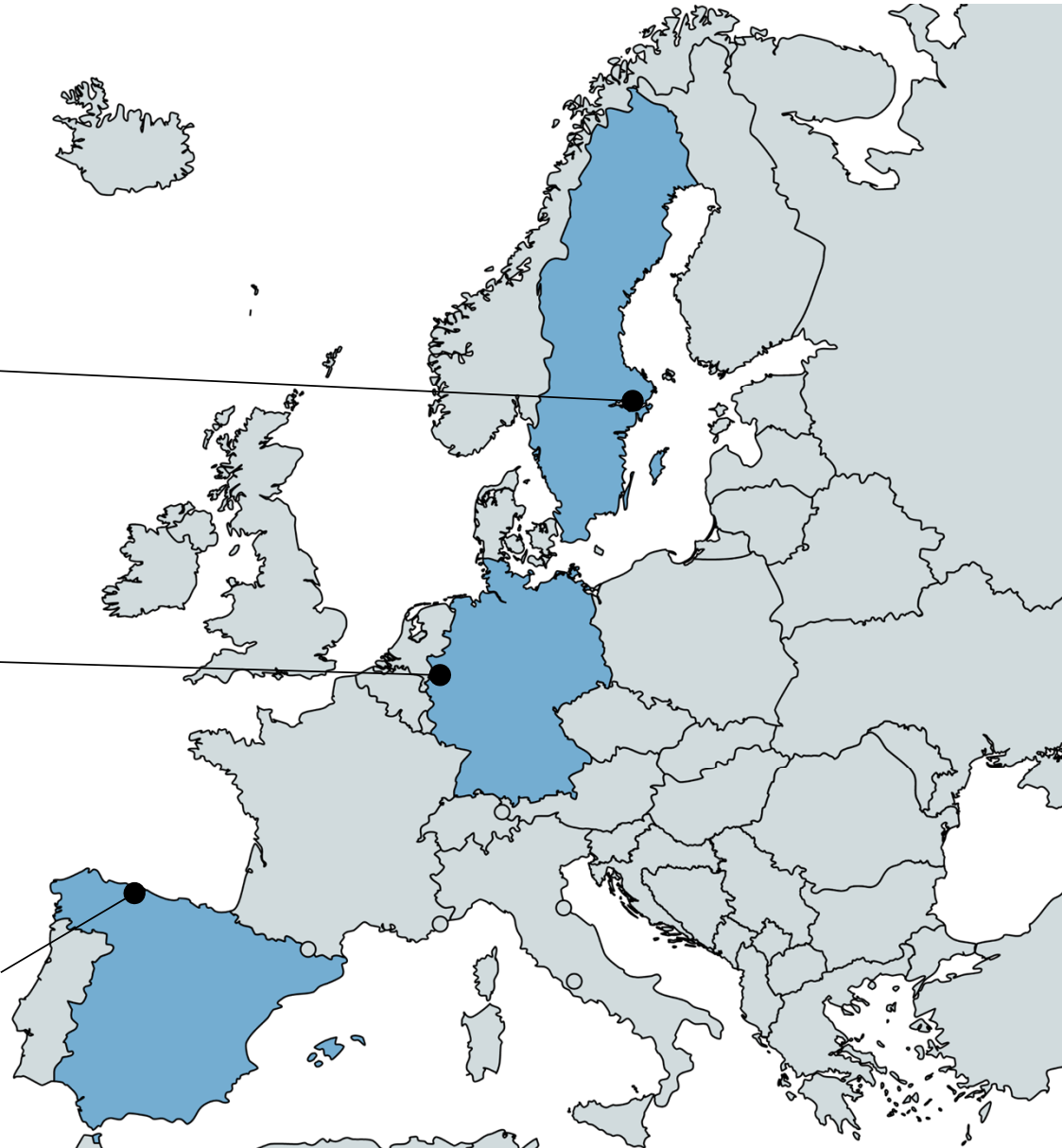


Alba Centeno

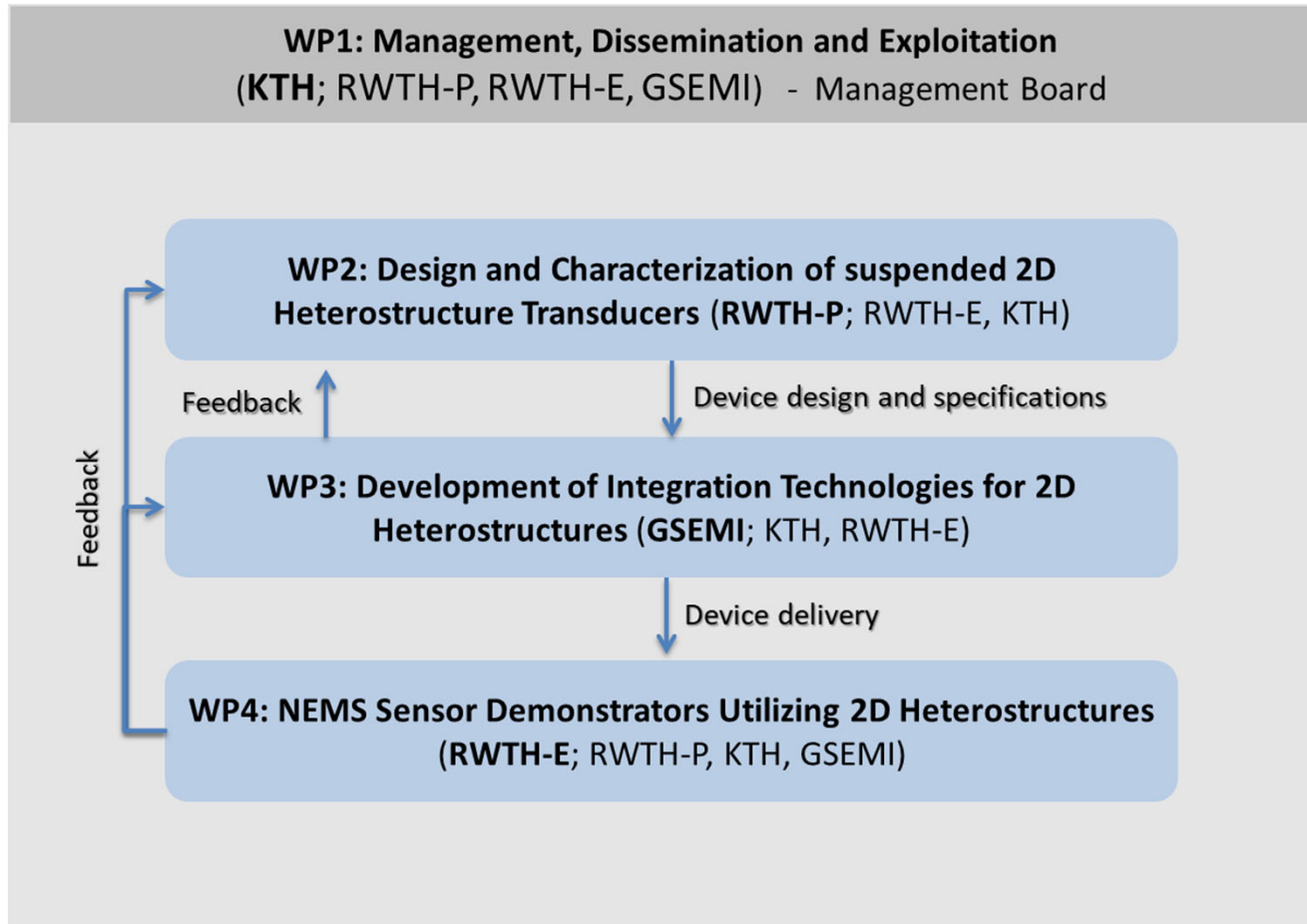
KTH

RWTH

Graphenea



Project organization



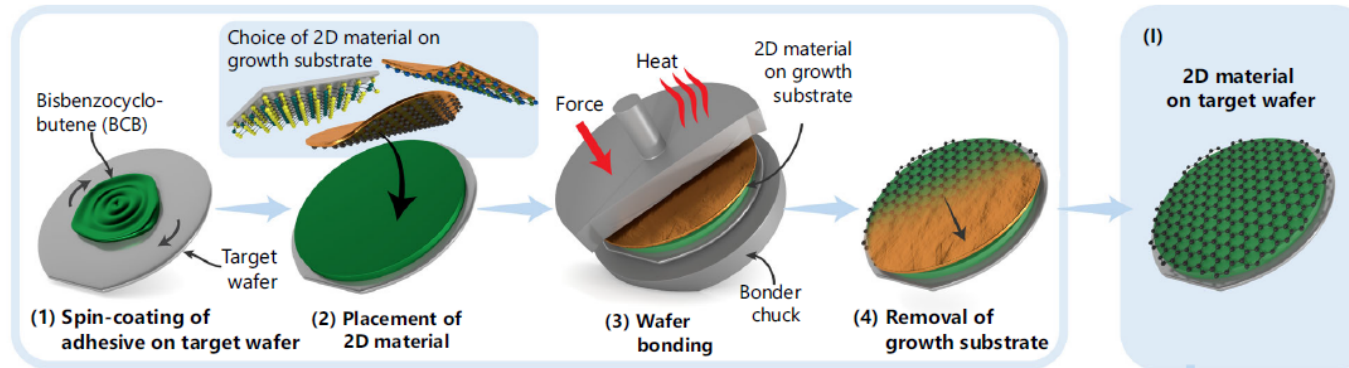


Interaction with Graphene Flagship

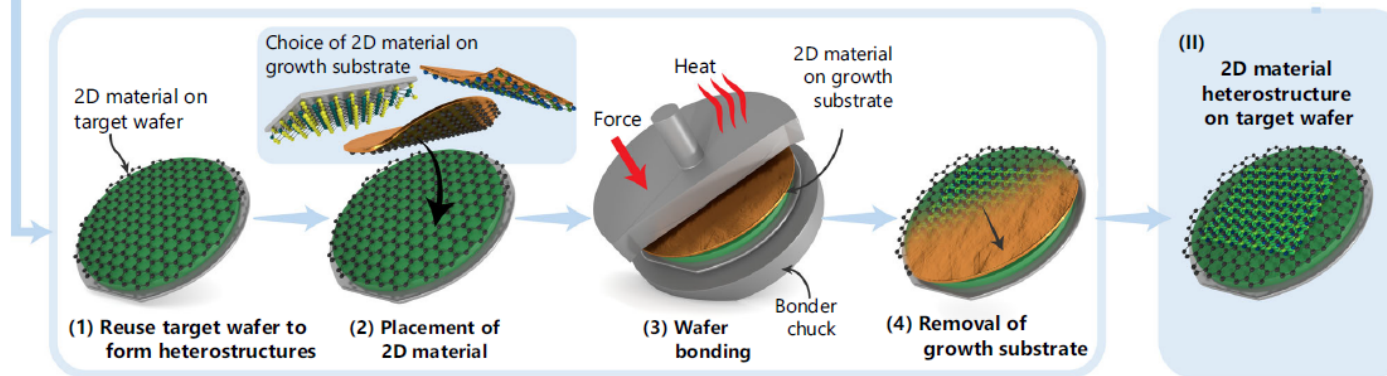
- RWTH and Graphenea are Flagship Core Partners, KTH is Associated Flagship Member.
- Synergies with multiple Flagship Work Packages:
 - Sensors, Enabling materials, Wafer-scale System Integration.
- 2D-NEMS members are involved in the new *2D-Experimental Pilot Line* project.
- 2D-NEMS members have parallel research collaborations with multiple core partners within Flagship: IMEC (Belgium), Uni. Bundeswehr München (Germany), ICN2 (Spain).
- 2D-NEMS results have been promoted by Flagship press team.

Large area production of 2D-material heterostructures

a Wafer-level transfer of 2D materials

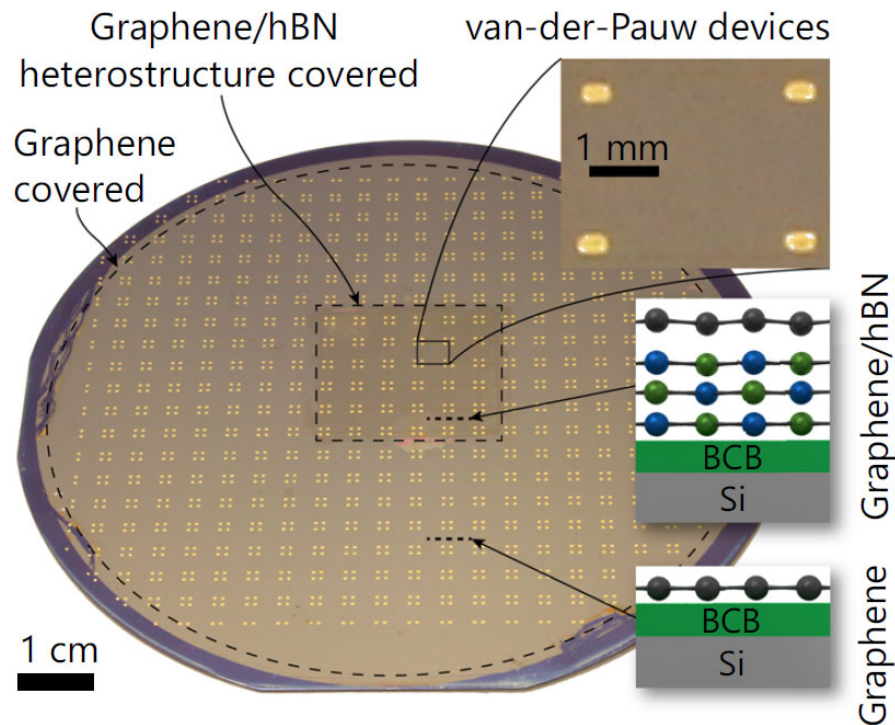


b Formation of 2D material heterostructures

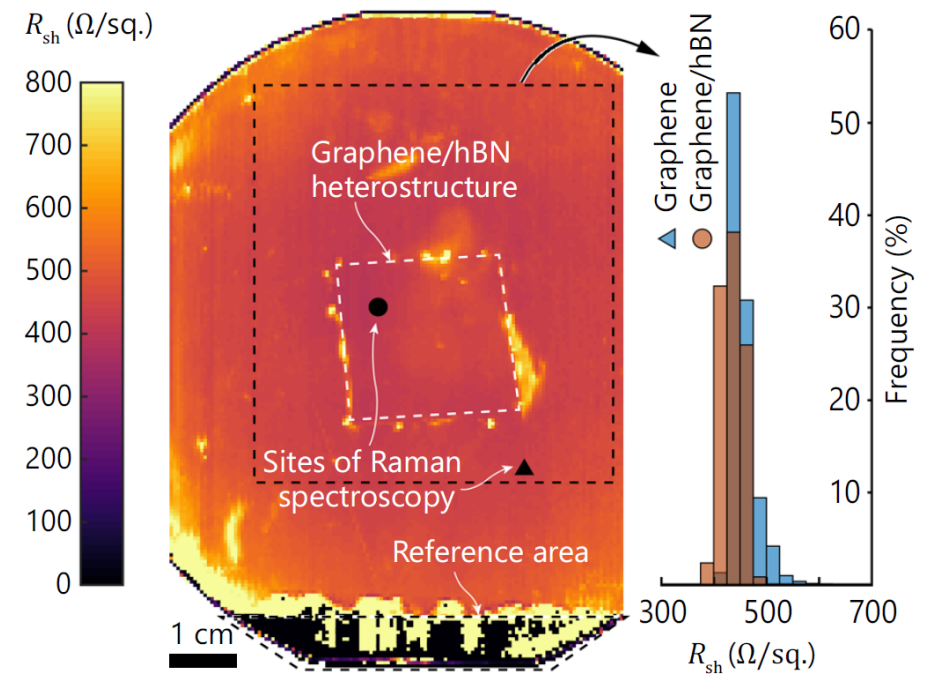


Large area production of 2D-material heterostructures

Graphene/hBN electronic devices

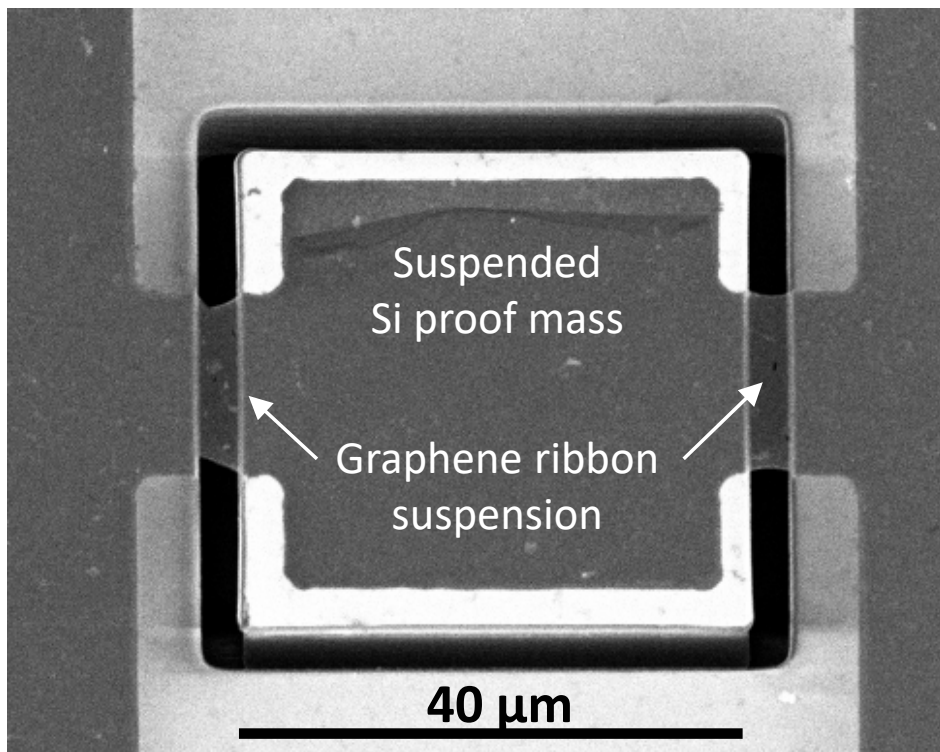


Wafer-scale heterostructure characterization

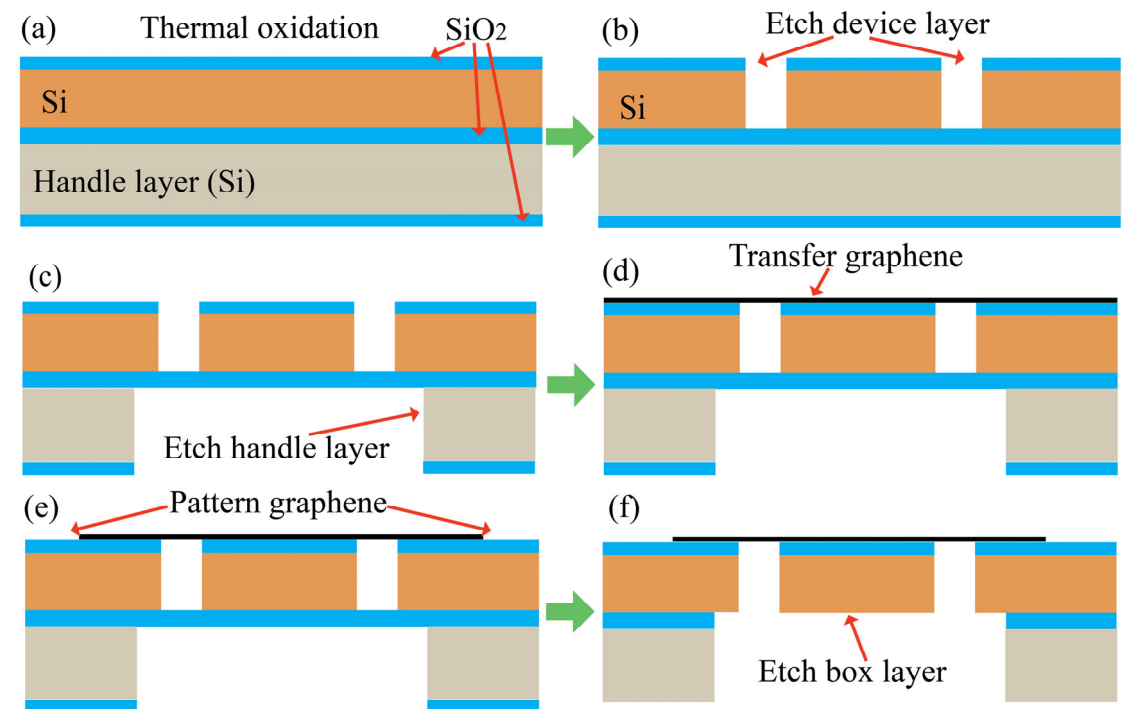


Graphene-based resonant accelerometers

Top view of accelerometer

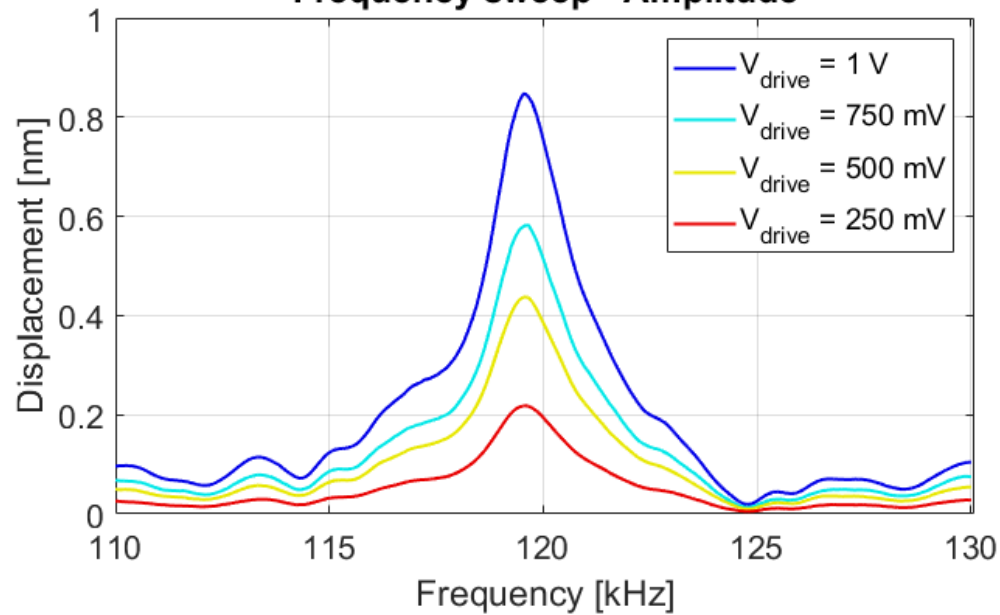


Fabrication (cross-section)



Graphene-based resonant accelerometers

Frequency sweep - Amplitude



Resonant Frequency shift for different accelerations

